

- [10] 2018/11/14@ Kamakura in JPN
17th International Conference on Precision Engineering (ICPE2018)
Absolute measurement of optical path length of the three-dimensional nanop profiler based on the normal vector tracing method by tandem white light interferometer
○[J. Kang](#), [T. Kitayama](#), [R. Kizaki](#), [T. Toyoshi](#), A. Winarno, K. Takamasu, [K. Yamamura](#), [K. Endo](#)
- [9] 2018/11/08@ Las Vegas in USA
33rd American Society for Precision Engineering Annual Meeting (ASPE2018)
High Accuracy Cylindrical Mirror Measurement by Three-dimensional Nano-profiler Based on the Normal Vector Tracing Method
○[J. Kang](#), [H. Shiraji](#), [R. Kizaki](#), [T. Toyoshi](#), [T. Kitayama](#), T. Miyawaki, [K. Yamamura](#), [K. Endo](#)
- [8] 2018/10/18@ St. Gallen in Switzerland
5th International Workshop Plasma Science & Interfaces
Adhesive-free strong adhesion between fluoropolymers and other materials via plasma-jet-treated polydimethylsiloxane
○[Y. Ohkubo](#), [K. Endo](#), [K. Yamamura](#)
- [7] 2018/08/20@ Saskachewan in Canada
XRM2018 (International Conference X-ray Microscopy)
Multislice Imaging Of Integrated Circuits By X-Ray Ptychography
○[K. Shimomura](#), [M. Hirose](#), [T. Higashino](#), [Y. Takahashi](#)
- [6] 2018/08/20@ Saskachewan in Canada
XRM2018 (International Conference X-ray Microscopy)
Nanoscale Chemical Imaging of Three-Way Catalyst Pt/Ce₂Zr₂O_x Particles By Ptychographic-XAFS
○[M. Hirose](#), N. Ishiguro, [K. Shimomura](#), H. Matsui, M. Tada, [Y. Takahashi](#)
- [5] 2018/06/28@ NY in USA
Coherence 2018: International Workshop on Phase Retrieval and Coherence Scattering
Three-dimensional chemical imaging of oxygen storage and release particles by hard X-ray spectro-ptychography
○[M. Hirose](#), N. Ishiguro, [K. Shimomura](#), H. Matsui, M. Tada, [Y. Takahashi](#)
- [4] 2018/06/28@ NY in USA
Coherence 2018: International Workshop on Phase Retrieval and Coherence Scattering
Multislice observation of integrated circuits by X-ray ptychography
○[K. Shimomura](#), [M. Hirose](#), [T. Higashino](#), [Y. Takahashi](#)
- [3] 2018/06/13@ Taipei in Taiwan
SRI 2018: International Conference on Synchrotron Radiation Instrumentation

Development and application of hard X-ray spectro-ptychography using Kirkpatrick-Baez mirrors

○M. Hirose, N. Ishiguro, K. Shimomura, H. Matsui, M. Tada, Y. Takahashi

● [2] 2018/06/07@ Venice in Italy

18th International Conference of the European Society for Precision Engineering and Nanotechnology

Application of Plasma Chemical Vaporization Machining for Figuring of Reaction-sintered Silicon Carbide

○R. Sun, Y. Ohkubo, K. Endo, K. Yamamura

● [1] 2018/04/26@ Bilbao in Spain

The 19th CIRP Conference on Electro Physical and Chemical Machining

AFM observation of initial oxidation stage of 4H-SiC (0001) in electrochemical mechanical polishing

○X. Yang, Y. Ohkubo, K. Endo, K. Yamamura